

FORM PTO-1449 US Dept. of Commerce Patent and Trademark Office		ATTORNEY DOCKET NO. ATMI-537-CIP	SERIAL NO. 10/632,009
INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)		APPLICANT Chongying Xu, et al.	DEC 24 2003 U.S. PATENT & TRADEMARK OFFICE
		FILING DATE July 31, 2003	GROUP 2812 2818

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
P D	AA	5,840,897	11/24/1998	Kirlin, et al.			
	AB	5,453,494	9/26/1995	Kirlin, et al.			
	AC	6,110,529	8/29/2000	Gardiner, et al.			
	AD	5,820,664	3/31/1995	Gardiner, et al.			
	AE	5,225,561	9/12/1990	Kirlin, et al.			
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	AH	5,211,342A	5/18/1993	Hoy, et al.			
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P D	AJ	10/632,009		Chongying Xu, et al.			11/25/2002

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		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY	CLASS	SUBCLAS S	TRANSLATION YES	NO
							X (abstract only)	

OTHER DOCUMENTS (Including Author, Title, Journal-Date, Page Number, Etc.)

P D	AK	Brian N. Hansen, et al., "Supercritical Fluid Transport-Chemical Deposition of Films" Chemical Materials, 1992, 4, 749-752.
P D	AL	Jason M. Blackburn, et al., "Deposition of Conformal Copper and Nickel Films from Supercritical Carbon Dioxide" Science, Vol 294, October 5, 2001, pgs. 141-145
P D	AM	C.Y. Xu, et al., "Supercritical Carbon Dioxide Assisted Aerosolization for Thin Film Deposition, Fine Powder Generation, and drug delivery", Green Chemistry, Editors: Anastas, Paul T., et al. Oxford University Press, Oxford, UK, pgs. 312-335.

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